## Dattatray S Wavhal

## List of Publications by Year

 in descending orderSource: https:/|exaly.com/author-pdf/9018789/publications.pdf
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Mechanisms of SiO 2 film deposition from tetramethylcyclotetrasiloxane, dimethyldimethoxysilane, 6 and trimethylsilane plasmas. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and

